

AMENDMENT

IN THE CLAIMS:

Please amend the claims as follows:

1. (Currently Amended) A method of manufacturing a crystal resonator using a crystal substrate, comprising the steps of:

forming a crystal resonator area and a side electrode shielding/formation ~~blocks~~
~~thereabout~~ block on said crystal substrate through etching by leaving a partial connection section,
~~and with both areas kept separate~~ said crystal resonator area and said side electrode
shielding/formation block being separated from each other ~~with~~ by a gap; and

applying vapor deposition through said gap diagonally toward ~~the~~ a side of said crystal
substrate, ~~producing an area where~~ whereby a film is formed on said side ~~and an in a first area~~
~~where~~ but film formation is prevented in a second area of said side due to by the existence of ~~the~~
said side electrode shielding/formation ~~blocks~~ block, and thereby forming an electrode film
bisected in the thickness direction of ~~the~~ said substrate on ~~the~~ said side.

2. (Currently Amended) The method of manufacturing a small crystal resonator according to
claim 1, wherein by adjusting the size of ~~the~~ said gap between said crystal resonator area and ~~the~~
said side electrode shielding/formation block, said side electrode shielding/formation block is
constructed ~~of~~ in an area where said bisected electrode film is formed and an area where
formation of the said electrode film is prevented.

3. (Currently Amended) The method of manufacturing a small crystal resonator according to
claim 1, wherein vapor deposition toward ~~the~~ said side of said crystal substrate is performed in a
range of angle of incidence of $\pm 45^\circ$ to 55° with respect to ~~the~~ said side ~~of the crystal substrate~~.

4. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1, wherein said electrode film is divided into upper and lower portions and is formed on ~~the side of the a~~ vibration section of ~~the said~~ crystal resonator.

5. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 4, wherein $0.15t \leq d \leq 0.25t$ is held where t is the thickness of said vibration section and d is the distance between ~~the two divided bisected~~ electrodes on ~~the said side of the~~ said side being on a tine for detection of Coriolis force.

6. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1,

wherein said crystal resonator is a quartz crystal tuning fork including a vibration section made up of a base and a plurality of vibration tines which extend from ~~the said~~ base, and wherein said electrode film is divided into upper and lower portions ~~is formed on the said~~ side said side being a side of the said vibration section and ~~the a~~ side of ~~the said~~ base.

7. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1,

wherein said crystal resonator is a resonator for a vibration gyro having three vibration tines, and wherein said electrode film is divided into upper and lower portions ~~is provided on the said side of the~~ said side being on a tine for detection of Coriolis force out of said three vibration tines.

8. (Original) The method of manufacturing a small crystal resonator according to any one of claims 1 to 7, wherein the thickness t of said crystal resonator is $100 \mu\text{m} \leq t \leq 350 \mu\text{m}$.

9. (Currently Amended) The method of manufacturing a small crystal resonator according to claim 1,

wherein said crystal resonator is a quartz crystal tuning fork including a vibration section made up of a base and a plurality of vibration tines which extend from ~~the~~ said base, and

wherein part of said side electrode shielding/formation block is provided ~~so as to insert~~ between said vibration tines.

10. (Previously Presented) A small crystal resonator created using the manufacturing method according to any one of claims 1 to 7 and 9.

11. (Previously Presented) A small crystal resonator created using the manufacturing method according to claim 8.